

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE PATENT APPLICATION OF: *JE A GUN PARK, ET AL.*  
SERIAL NO.: *10/540,992*  
ATTORNEY DOCKET NO.: 061063-0316598  
FILING DATE: June 5, 2006  
CONFIRMATION NO. 9014  
ART UNIT: 1792  
EXAMINER: ANGADI, Maki A.  
FOR: CHEMICAL-MECHANICAL-POLISHING SLURRY COMPOSITION, METHOD FOR PLANARIZING SURFACE OF SEMICONDUCTOR DEVICE USING THE SAME, AND METHOD FOR CONTROLLING SELECTION RATIO OF SLURRY COMPOSITION

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### **RESPONSE TO FINAL OFFICE ACTION WITH REQUEST FOR CONTINUED EXAMINER UNDER 37 CFR § 1.114**

#### **Mail Stop RCE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Final Office Action mailed February 20, 2009, the date for responding being May 20, 2009, and in conjunction with the Request for Continued Examination (RCE) filed concurrently herewith, please amend the above-identified application as follows:

**Amendments** to the claims begin on page 2 of this paper.

**Remarks/Arguments** begin on page 6.

It is believed that no extensions of time or fees for net addition of claims are required beyond those that may otherwise be provided for in documents accompanying this paper. However, if additional extensions of time are necessary to prevent abandonment of this application, then such extensions of time are hereby petitioned for under 37 C.F.R. § 1.136(a), and any fees required therefore (including fees for net addition of claims) are hereby authorized to be charged to our Deposit Account No. 033975 (Ref. No. **061063-0316598**).